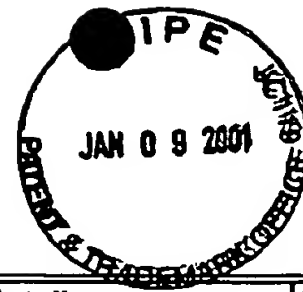


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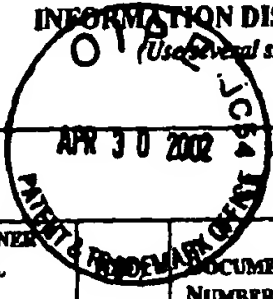
PATENTSheet 1 of 1

FORM PTO-1449 (Modified) (Rev. 7-80)		U.S Dept. of Commerce Patent and Trademark Office		Atty Docket No. TWI-10820		Appln. No. 09/629,407	
INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)				Applicant(s) Allan Rosencwaig et al.			
				Filing Date August 1, 2000		Group 2876	
U.S. PATENT DOCUMENTS							
*Examiner Initials	Document Number	Date	Name	Class	Subclass	Filing Date	
HKS	AA	5,371,582	12/06/1994	Toba et al.	356	73	07/30/1993
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HKS	AE	0 352 740	07/25/1989	EPC	H01L	21/306	
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	AG						
OTHER DOCUMENTS							
	AH						
	AI						
Examiner <i>Alton Song</i>				Date Considered <i>2/26/04</i>			
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	TWI-10820		09/629,407
	Applicant(s)		
	Allan Rosencwaig et al.		
Filing Date		Group Art Unit	
August 1, 2000		2876	



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*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE

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	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
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HKS	CB	E. Loken et al., "Growth monitoring of W/Si X-ray multilayers by X-ray reflectivity and kinetic ellipsometry," SPIE, Vol. 2253. November 1994, pp. 327-332.						

Examiner <i>Hoon Song</i>	Date Considered <i>2/26/04</i>
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